



Institute of Electrical Engineering SAS

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SC characterization at IEE Bratislava

IEE OVERVIEW

2023 – Sample Batches investigated:

Deposition: STFC Daresbury Laser treatment: Riga Technical Uni

• Laser-treated **Nb** films on **Cu** substrates — 3.2.2023 series

prepared at STFC Daresbury:

• V₃Si films on Cu and Sapphire substrates - 16.3.2023 series

Lasered Nb/Cu samples

Table-summary

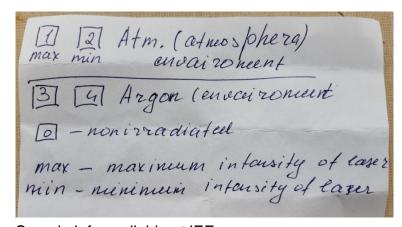
	Sample	Ben [Oe] (2% crit. at 4.22 K) Perpend Parallel	Tc [K]
Nb / Cu	0_Non_irr	240	9.25
	1_Atm_Laser_max	90	9.15
Arturs RTU	2_Atm_Laser_min	310	9.1
3.2.2023 series	3_Argon_Laser_max	₩	7 ?
	4_Argon_Laser_min	2	7 ?

Results ~OK:

- 0 non-irradiated
- 1 irradiated in "Atmosphere", Max intensity (vacuum/low pressure? air??)
- **2 –** irradiated in "Atmosphere", min intensity (vacuum/low pressure? air??)

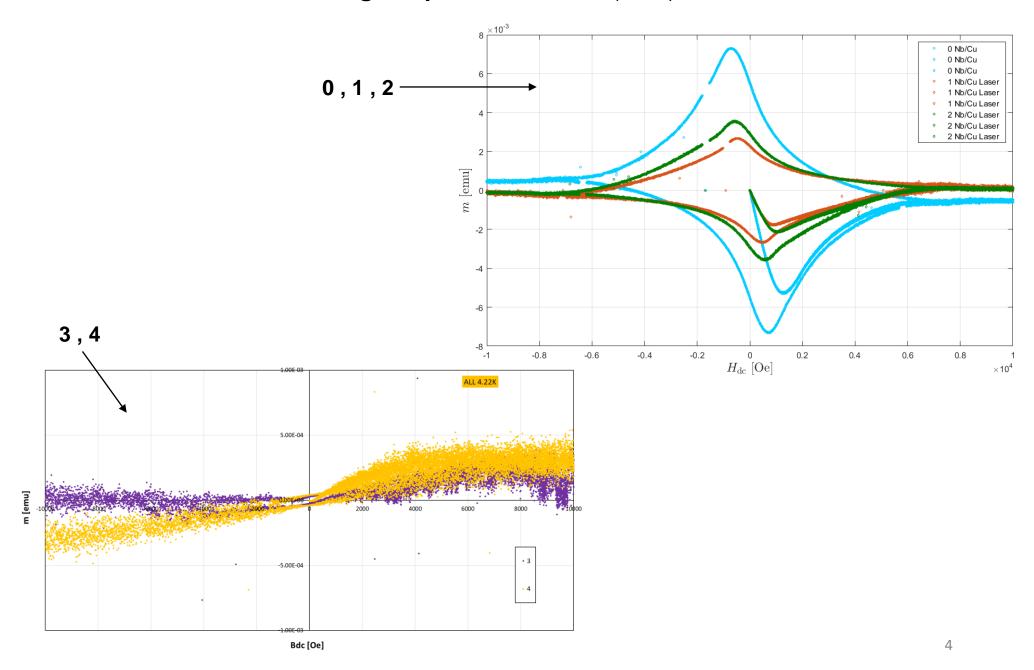
Very poor:

- 3 irradiated in Argon, Max intensity
- **4** irradiated in Argon, min intensity

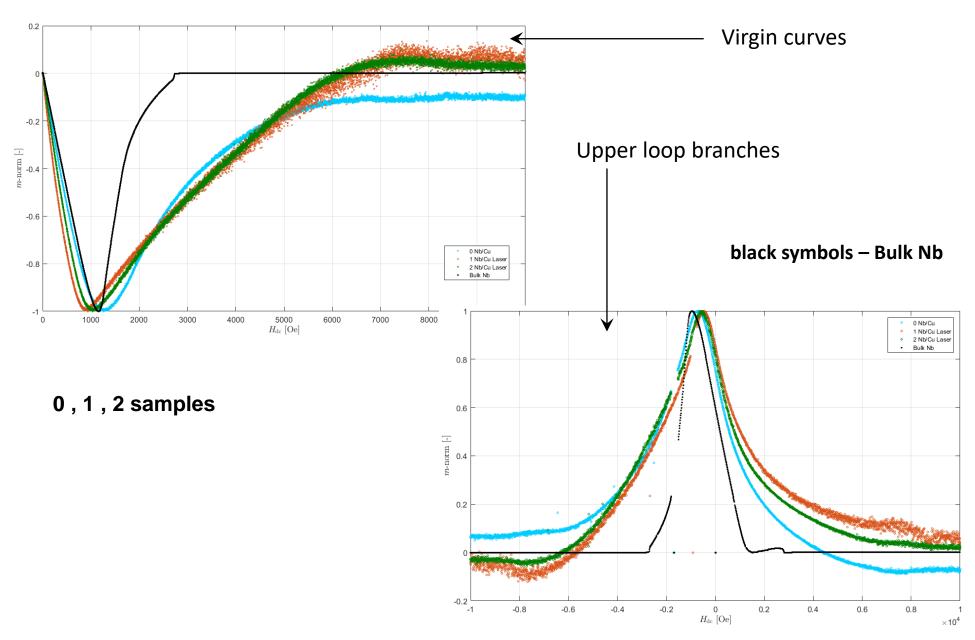


Sample info available at IEE

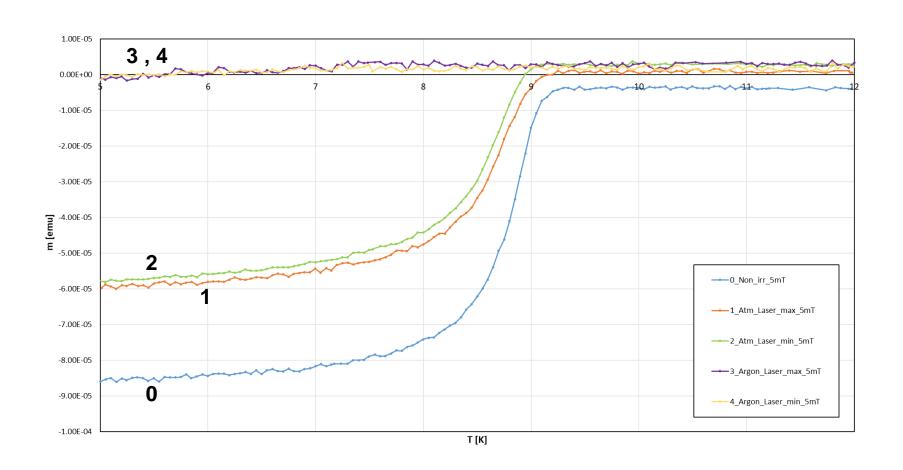
Mag Loops, as measured (4.2K)



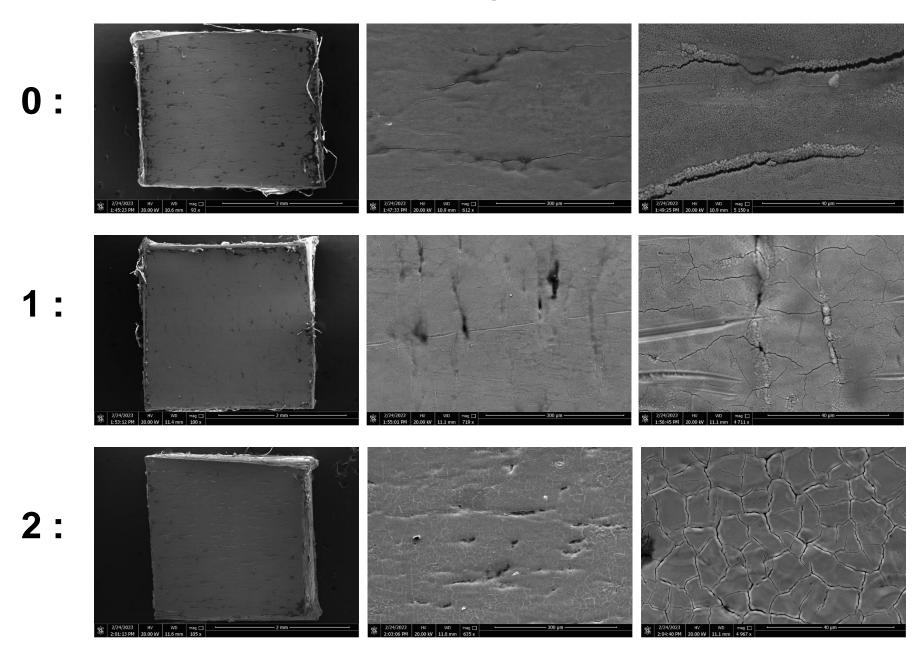
Normalised to Max



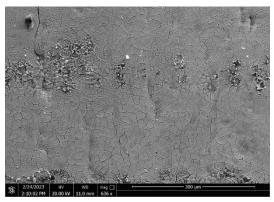
Temperature dependence m(T)

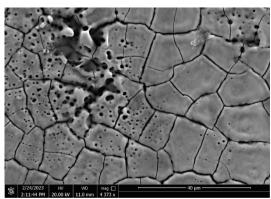


SEM micrographs

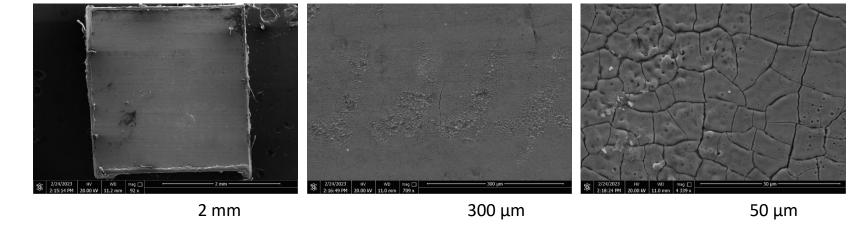


3 :





4:

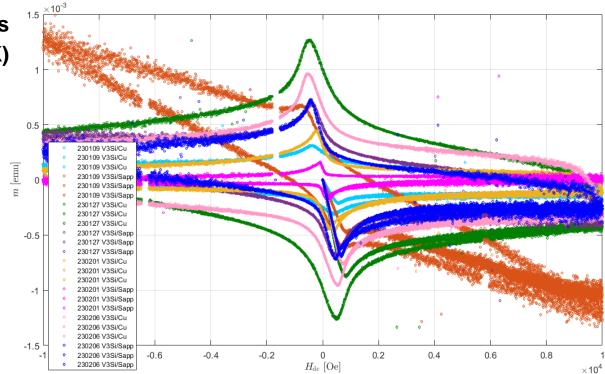


V₃Si samples on Cu & Sapphire

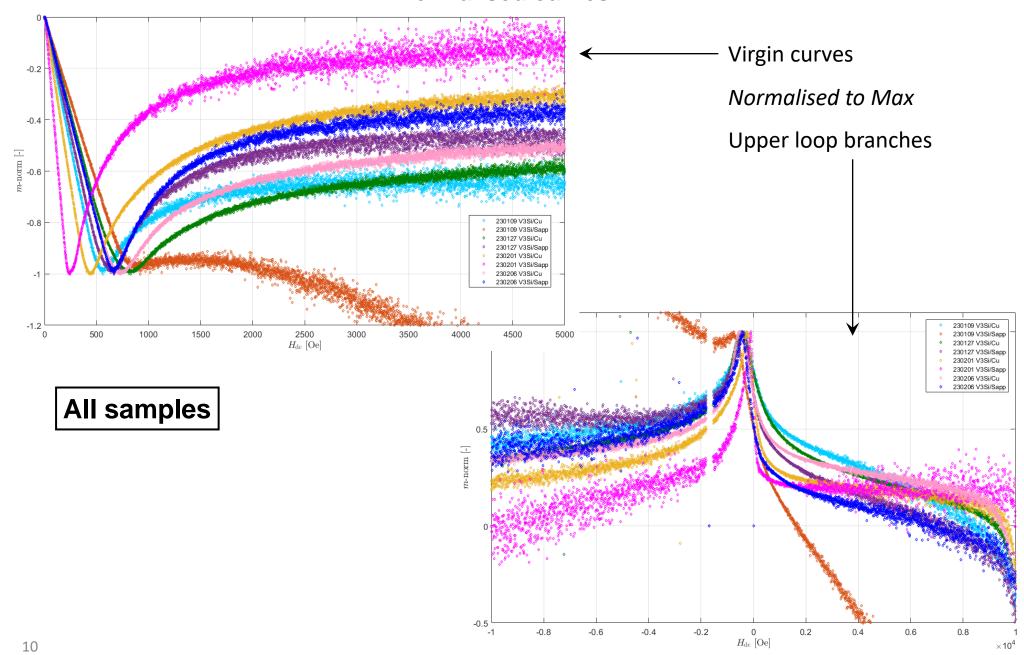
Summary

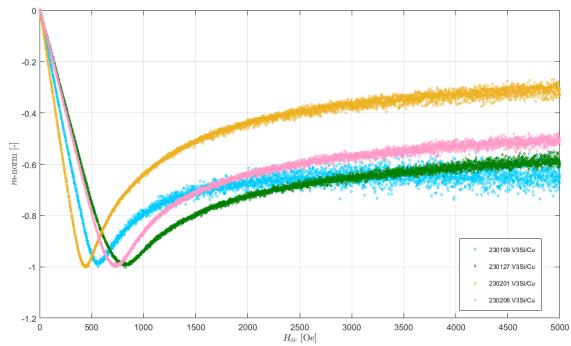
	Ben [Oe] Sample	Tc [K]	
		Perpend Parallel	
V3Si	230109_Cu	190	12.8
Substrates: Cu, Sapphire	230109_Sapp	610	14
	230127_Cu	510	13
STFC	230127_Sapp	470	11.5
16-03-23	230201_Cu	330	10.5
	230201_Sapp	200	8.2
	230206_Cu	530	12.5
	230206_Sapp	580	11.5

All samples raw loops (4.2K)

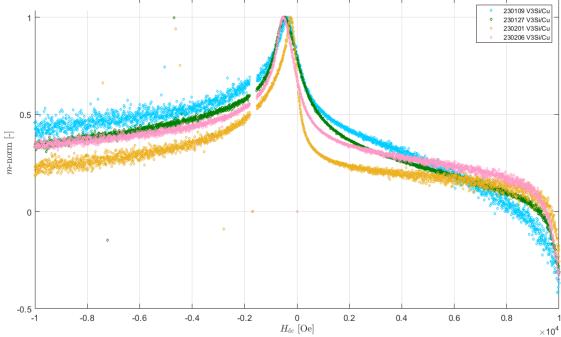


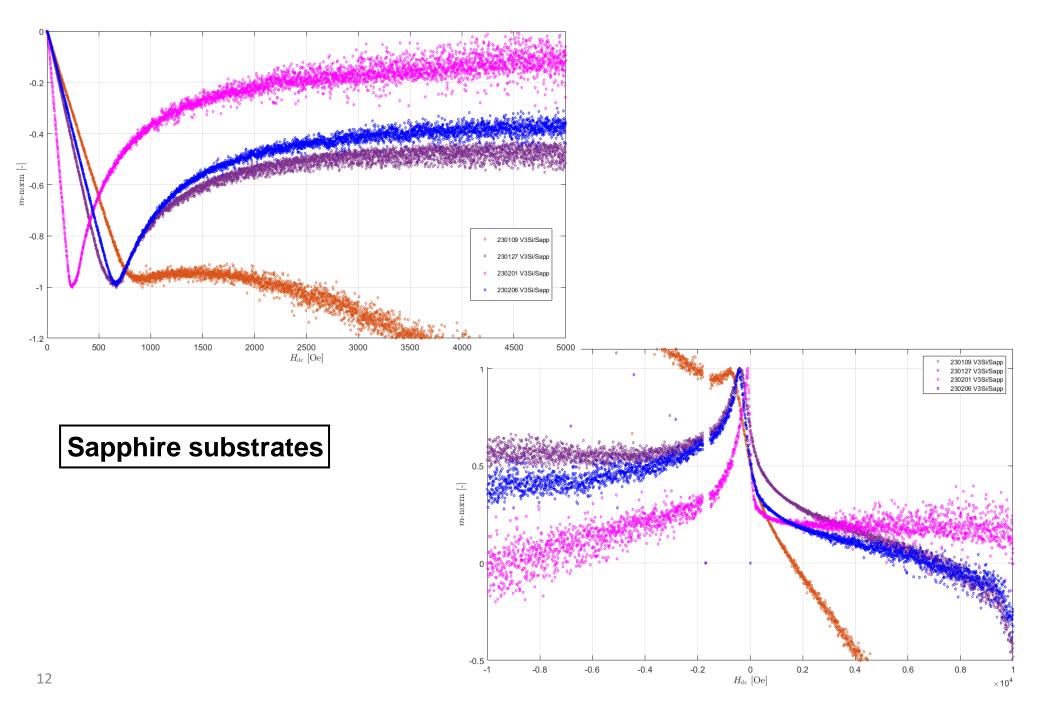
Normalised curves



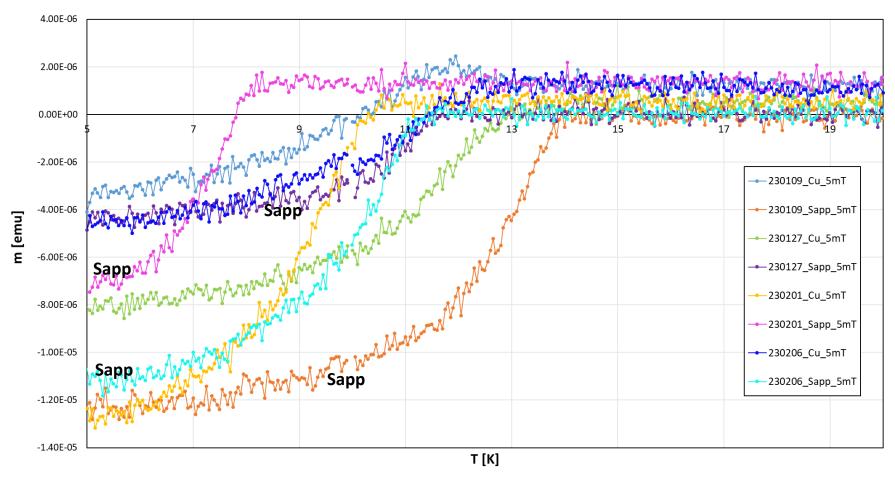


Cu substrates





Temperature dependence m(T)



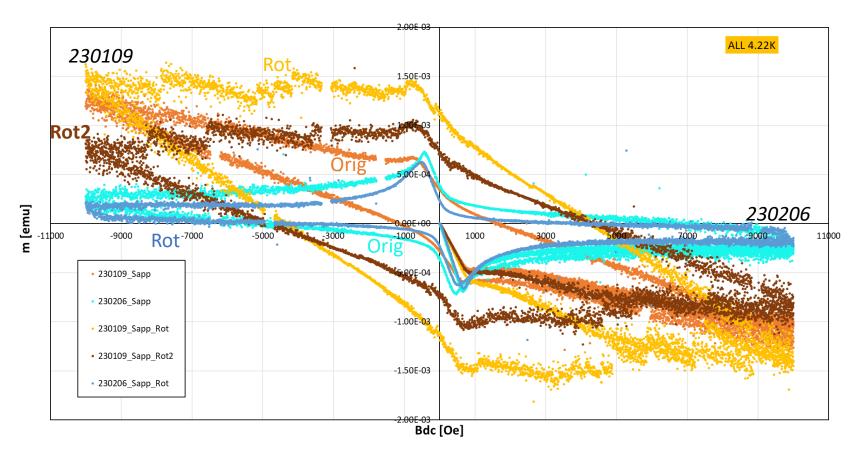
 $20K \rightarrow 5K$, 5mT applied field

Thanks for your attention

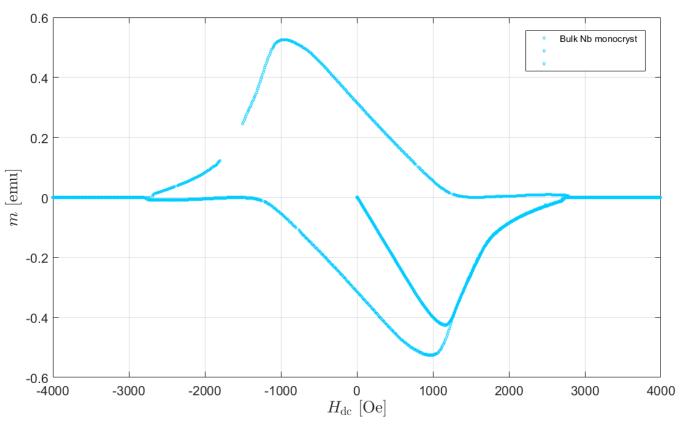
V₃Si

Sapphire substrates

Raw loops, Re-measured after sample rotation 90° (230109, 230206)



Mag Loop – Bulk Nb monocrystalline, CEA



"raw" Loop (absolute m)

(at 4.2 K)